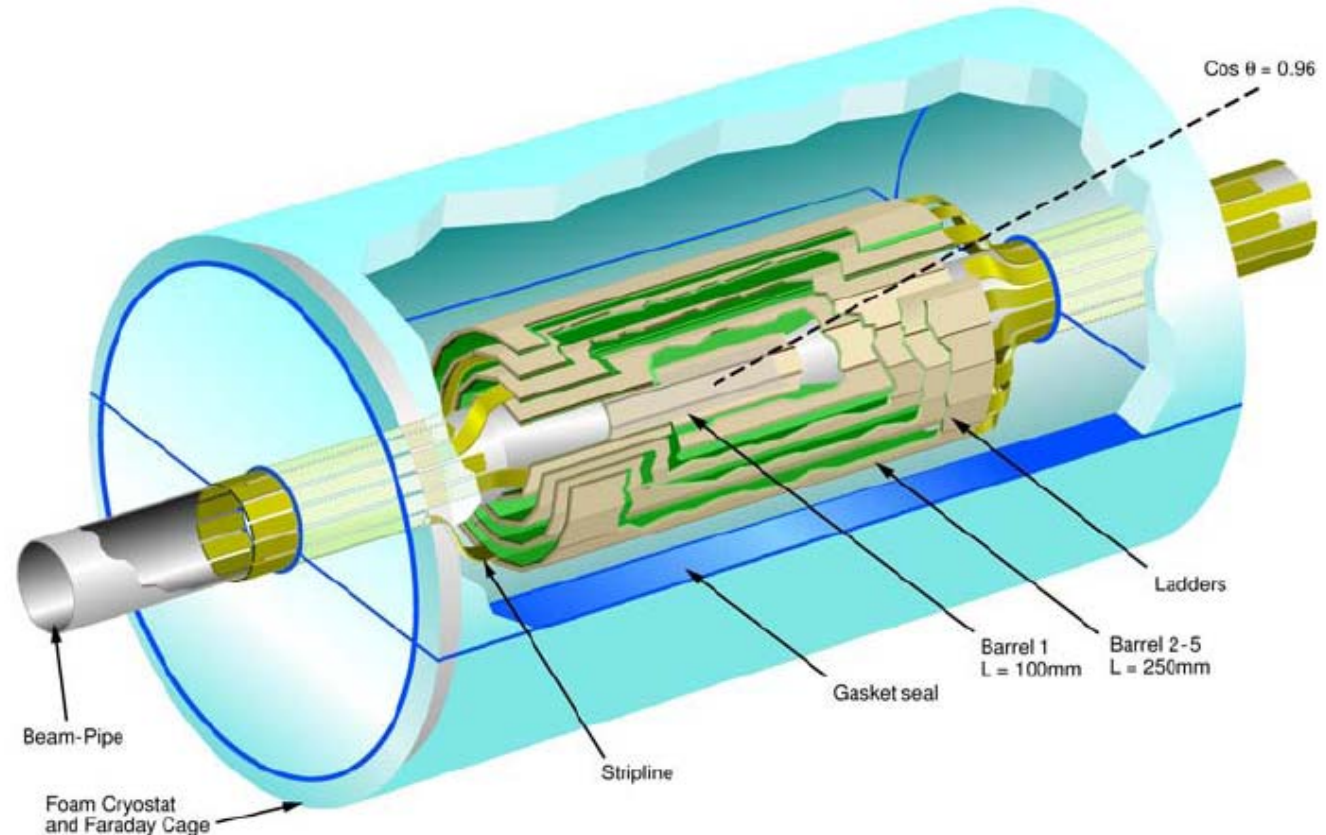


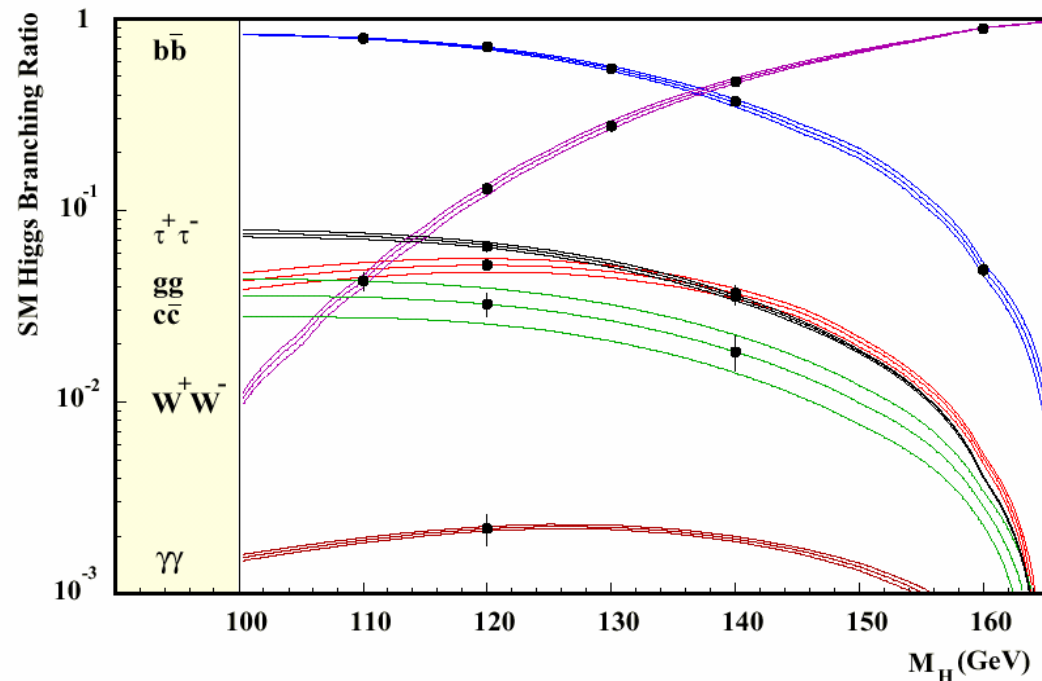
# Studies of Sensors for the ILC

- Introduction
- Studies of Column Parallel CCDs
- Design of In-situ Storage Image Sensors
- CMOS sensors
- Thin support structures for silicon sensors
- Other UK plans
- Summary



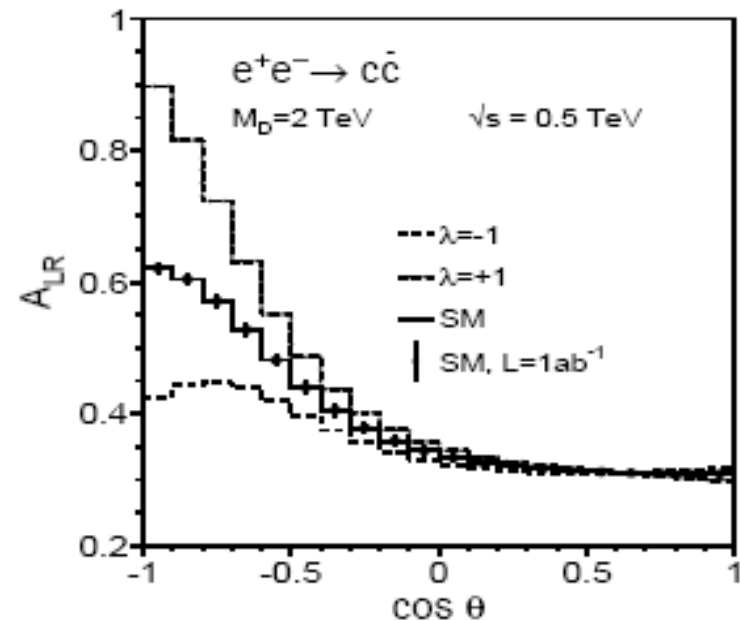
# Introduction – physics at the ILC

- The Int  $e^+e^-$  LC and its detectors will allow precise measurements of cross sections, masses, branching ratios...
- E.g. Branching ratios of Higgs boson:



- Requires quark flavour identification.

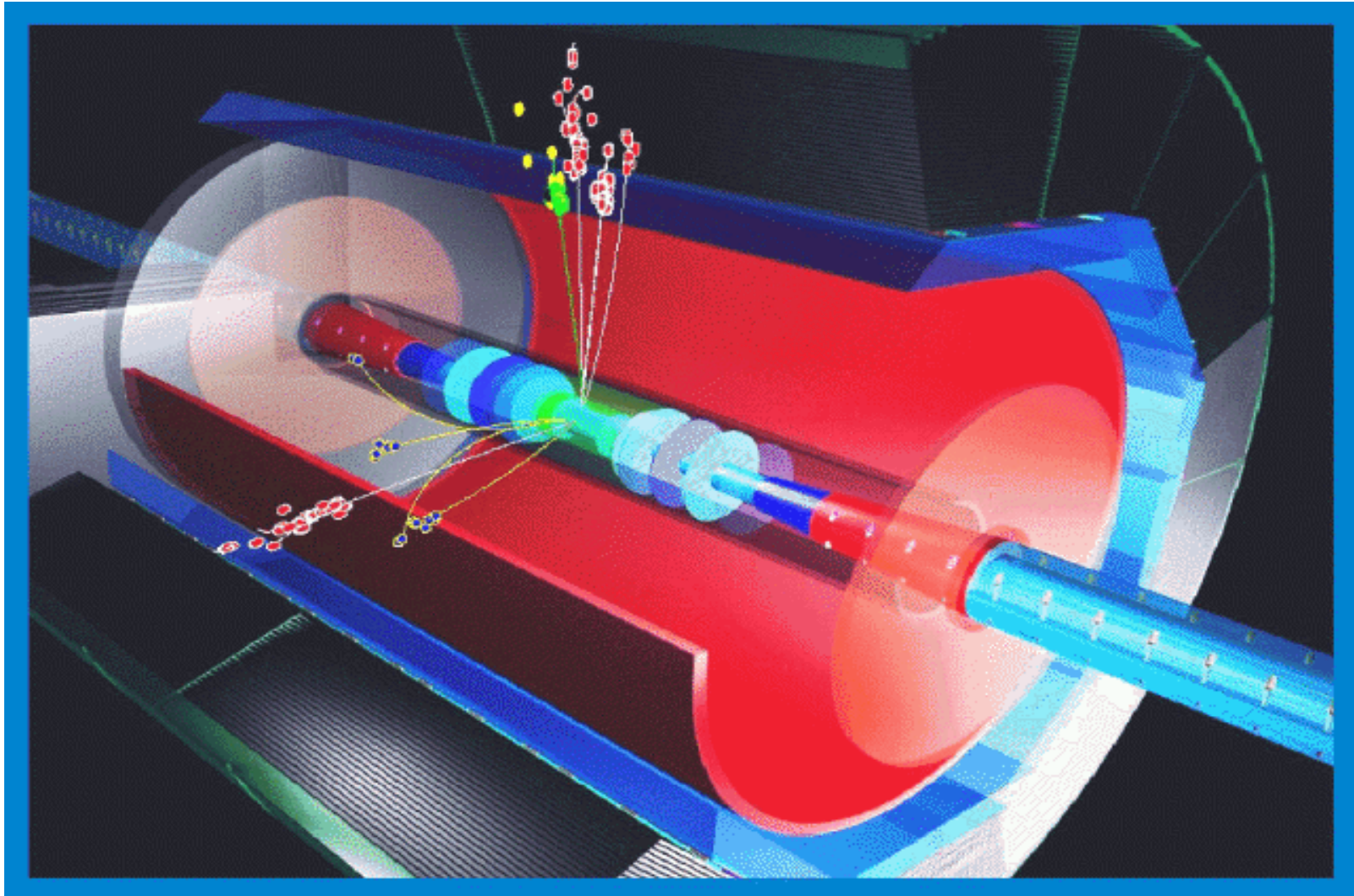
- Contribute to understanding of mass, dark matter, structure of space-time...
- E.g. effects of large extra dimensions on  $A_{LR} = (\sigma_L - \sigma_R)/\sigma_{tot}$  as a function of  $\cos \theta$  in process  $e^+e^- \rightarrow f\bar{f}$ .



- Requires quark charge identification.

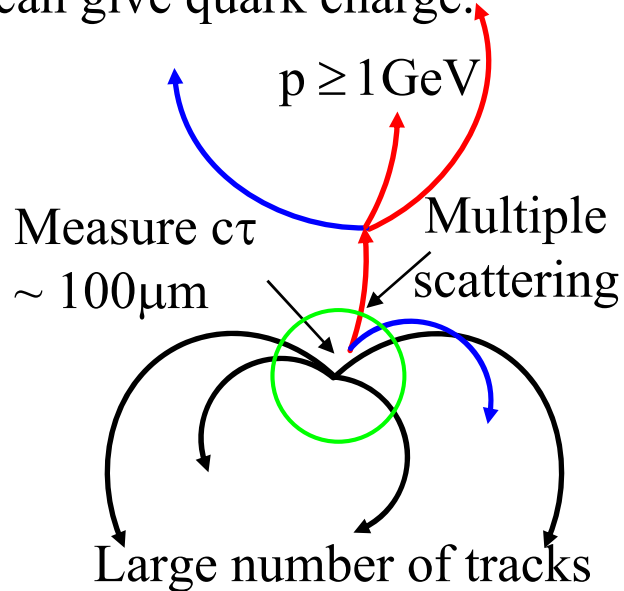
# Schematic of ILC detector

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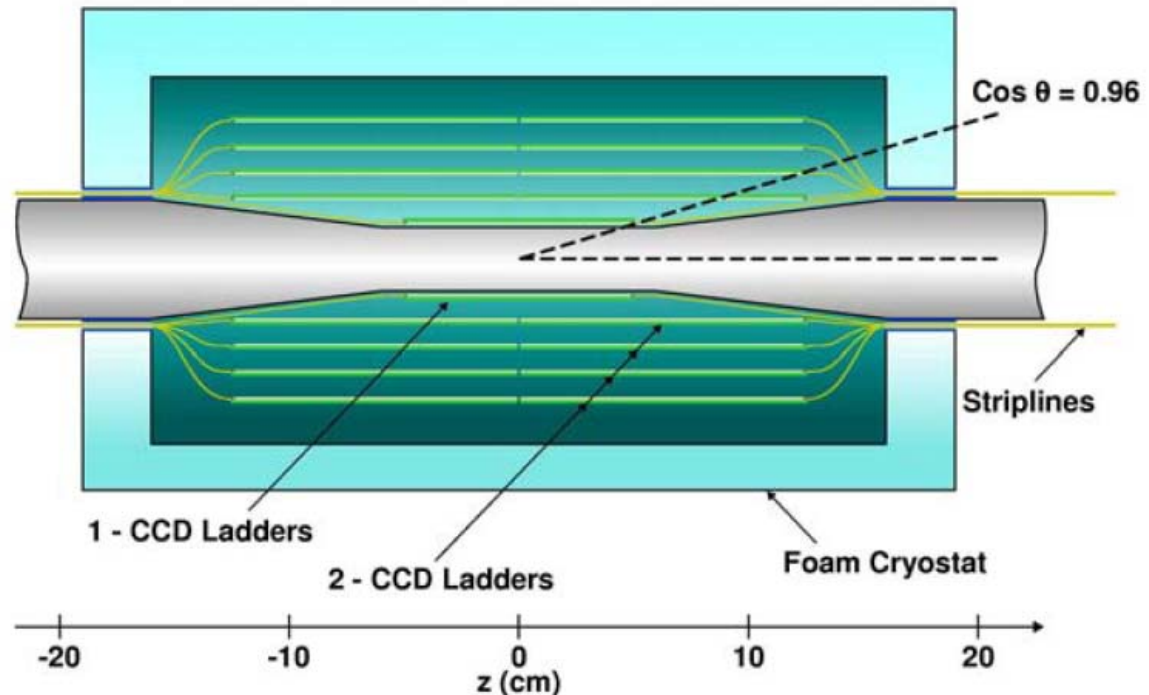
# Requirements on the ILC vertex detector

- Identify quark flavour by measuring distance hadrons fly before decay.
- Net charge of particles from vertices can give quark charge.



- Point precision  $< 5 \mu\text{m}$  needed.
- Two track resolution  $< 40 \mu\text{m}$ .
- Pixels  $\sim 20 \times 20 \mu\text{m}^2$  suffice.

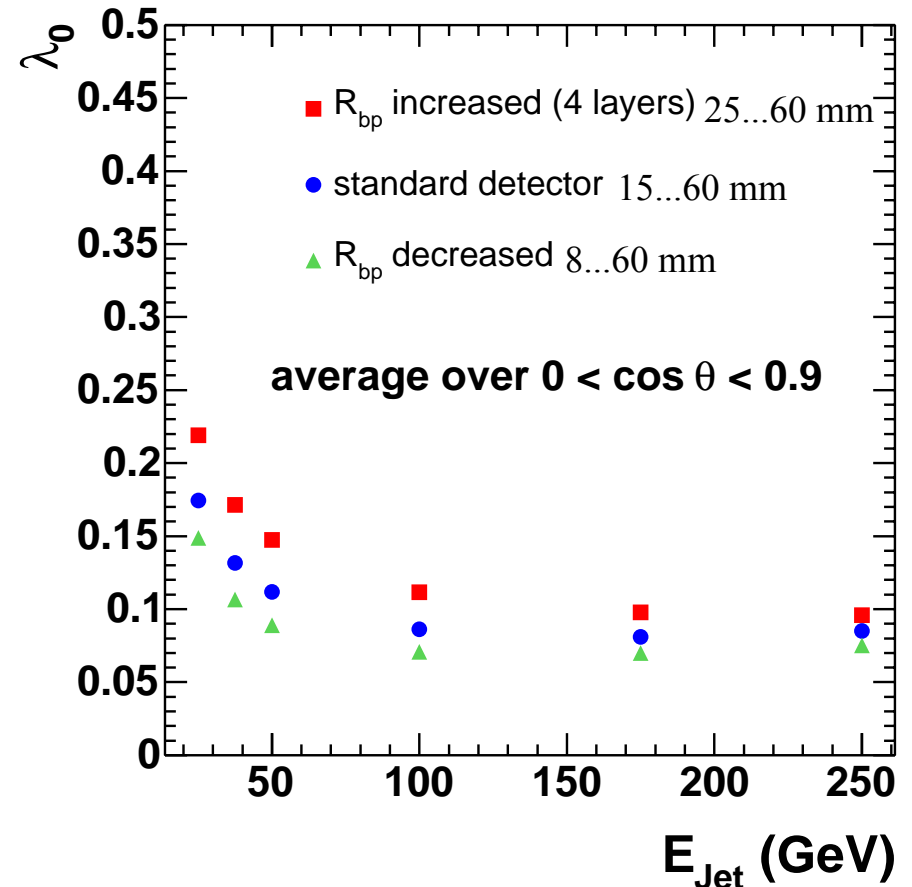
- Layer thickness  $< 0.1\% X_0$ .
- First measurement at  $r \sim 1.5 \text{ cm}$ .
- Need  $\sim 5$  layers to allow pattern recognition.
- Leads to vertex detector design:



# Quark charge identification performance

- Quantify performance in terms of  $\lambda_0$ , probability of reconstructing neutral B hadron as charged.
- Investigate effects of changing detector inner radius.
- Larger BP radius implies thicker BP:
  - ◆  $R_{BP} = 14$  mm,  $t = 0.4$  mm.
  - ◆  $R_{BP} = 25$  mm,  $t = 1.0$  mm.
- Significant loss of performance with increasing  $R_{BP}$ .
- Can express in terms of effective luminosity loss.
- For  $E_{Jet} = 25$  GeV and  $R_{BP} = 25$  mm, must inc. lumi. by factor  $\sim 1.7$  w.r.t  $R_{BP} = 15$  mm to get same error.

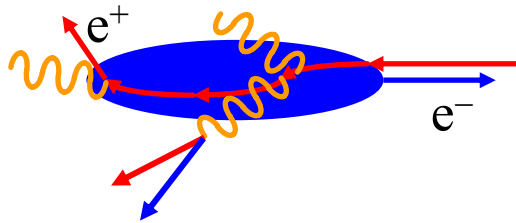
- $\lambda_0$  for different detector configurations:





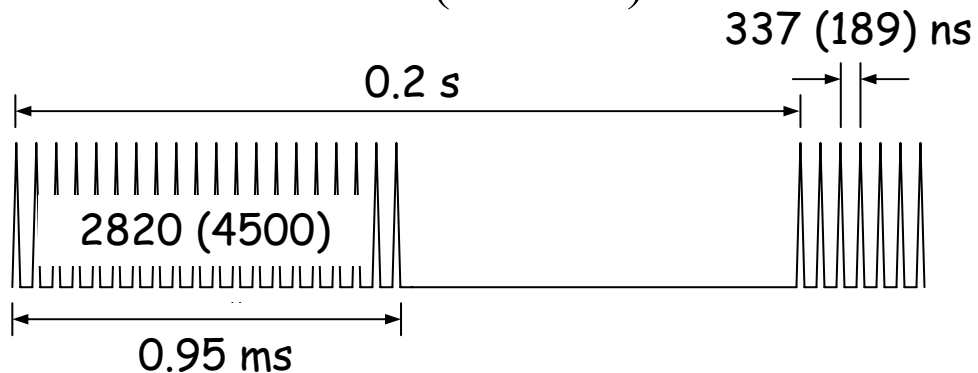
# Constraints on the vertex detector due to the ILC

- Beamstrahlung...



- ...results in production of  $\sim 5$  hits/cm<sup>2</sup> each bunch crossing in inner layer ( $B = 4\text{T}$ ,  $\sqrt{s} = 500\text{ GeV}$ ).

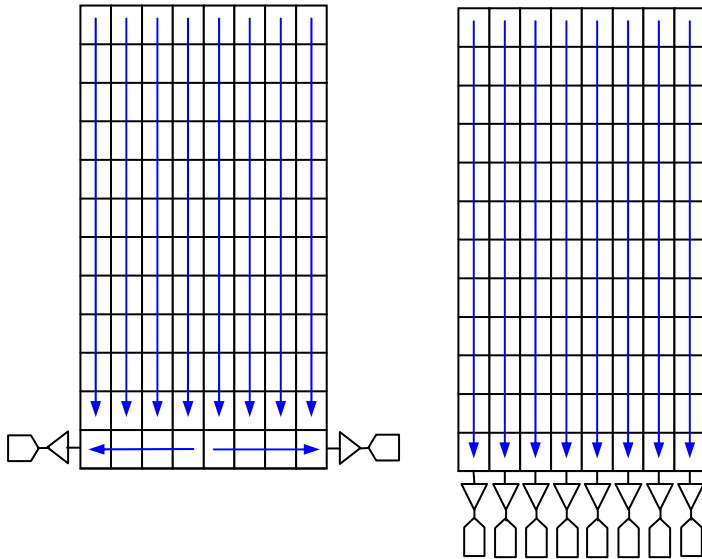
- Time structure of beam at  $\sqrt{s} \sim 500\text{ GeV}$  ( $\sim 1\text{ TeV}$ ):



- Readout pixels 20 times in bunch train at  $\sqrt{s} = 500\text{ GeV}$ , i.e.  $\sim$  every  $50\ \mu\text{s}$ , if want occupancy  $\sim 0.3\%$ .
- Radiation dose  $\sim 20\text{ krad p.a.}$
- Neutron background from interactions of  $e^+$  and  $e^-$  in beam dumps  $\sim 10^9\ 1\text{ MeV n/cm}^2\text{ p.a.}$
- Electromagnetic interference generated by  $e^+$  and  $e^-$  beams.
- Beam induced pick-up disabled the electronics of the SLD vertex detector for  $\sim 1\ \mu\text{s}$  after each bunch crossing.

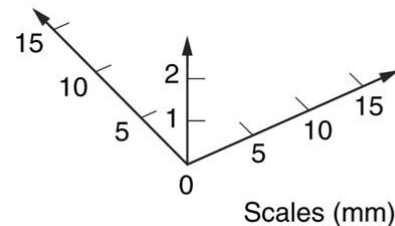
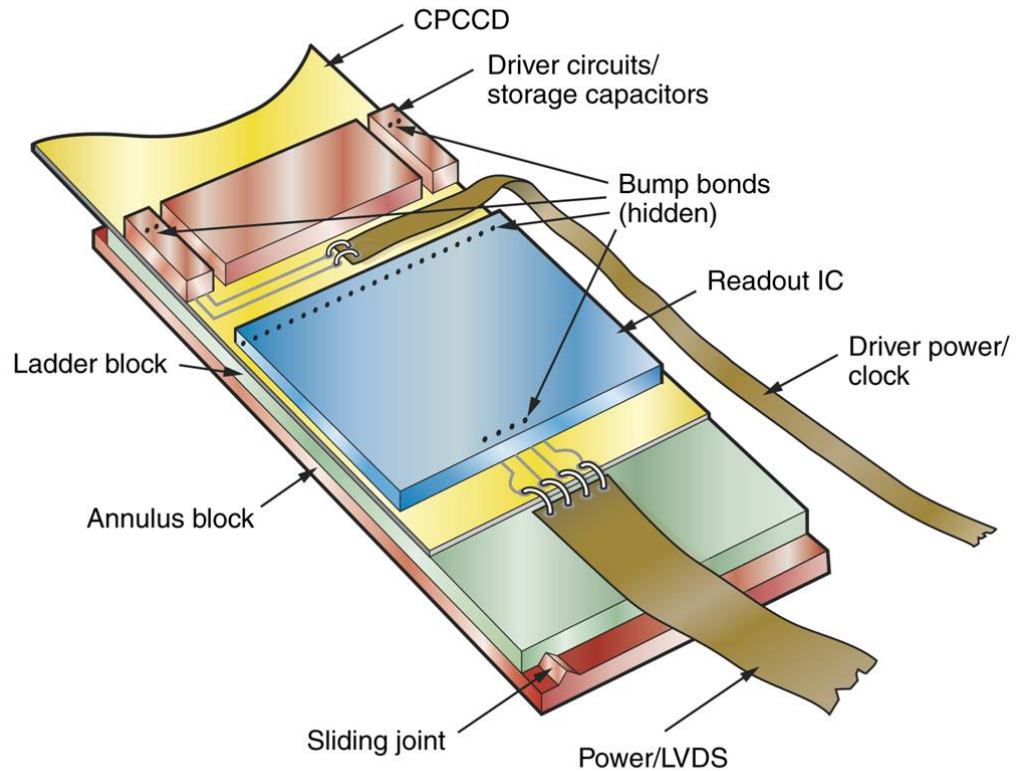
# Column Parallel CCDs

- Achieve necessary readout speed with CCDs using column parallel architecture:



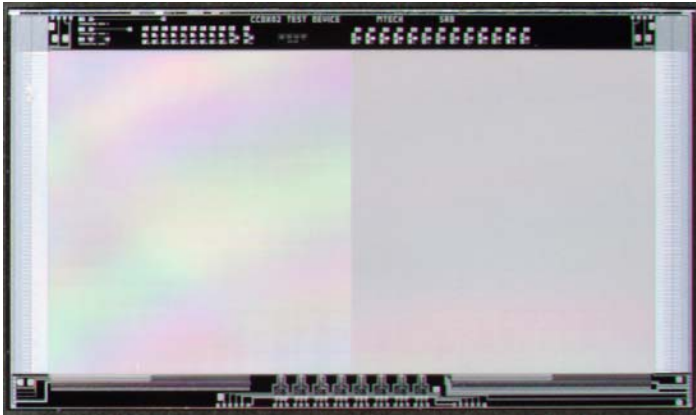
- Must drive image register at 50 MHz to readout in 50  $\mu$ s.

- Conceptual “ladder” design:



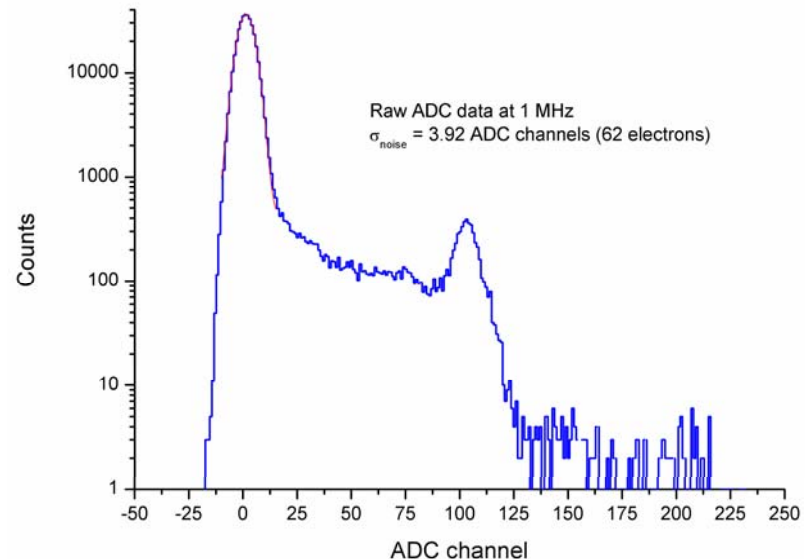
# CPC1

- First of these, CPC1, manufactured by e2v.



- Two phase, 400 (V)  $\times$  750 (H) pixels of size  $20 \times 20 \mu\text{m}^2$ .
- Metal strapping of clock gates.
- Two-stage and one-stage source follower and direct (charge) outputs.

- Standalone CPC1 tests:
- Noise  $\sim 100 e^-$  ( $60 e^-$  after filter).
- Minimum clock potential  $\sim 1.9 \text{ V}$ .

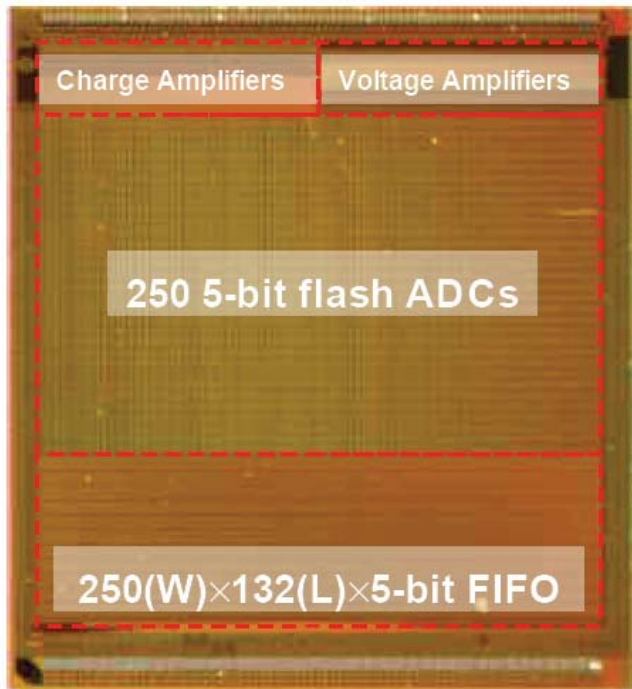


- Max clock frequency above 25 MHz (design 1 MHz).



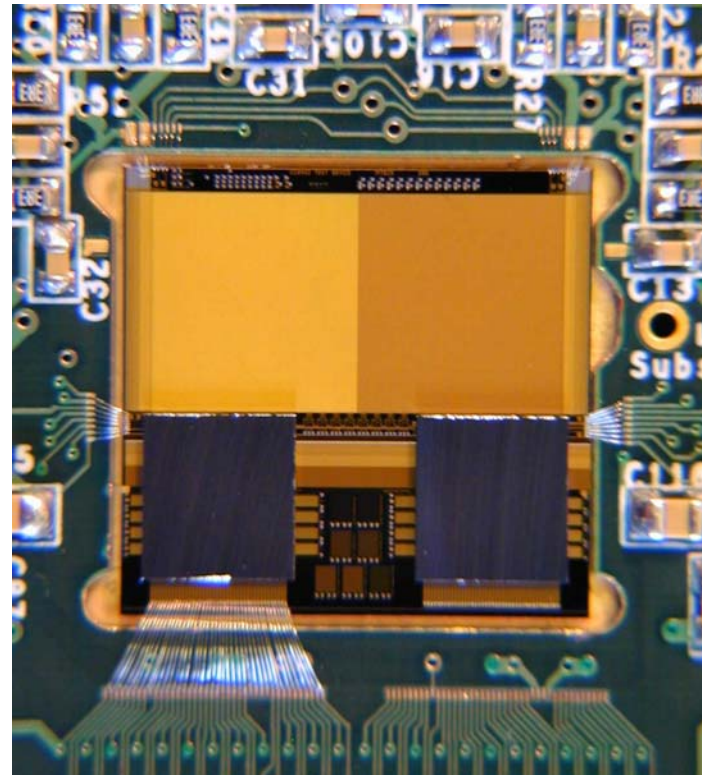
# CPC1 bump-bonded to CPR1 readout chip

- Marry with CMOS CPCCD readout ASIC, CPR1 (RAL):



- IBM 0.25  $\mu\text{m}$  process.
- 20  $\mu\text{m}$  pitch, designed for 50 MHz.

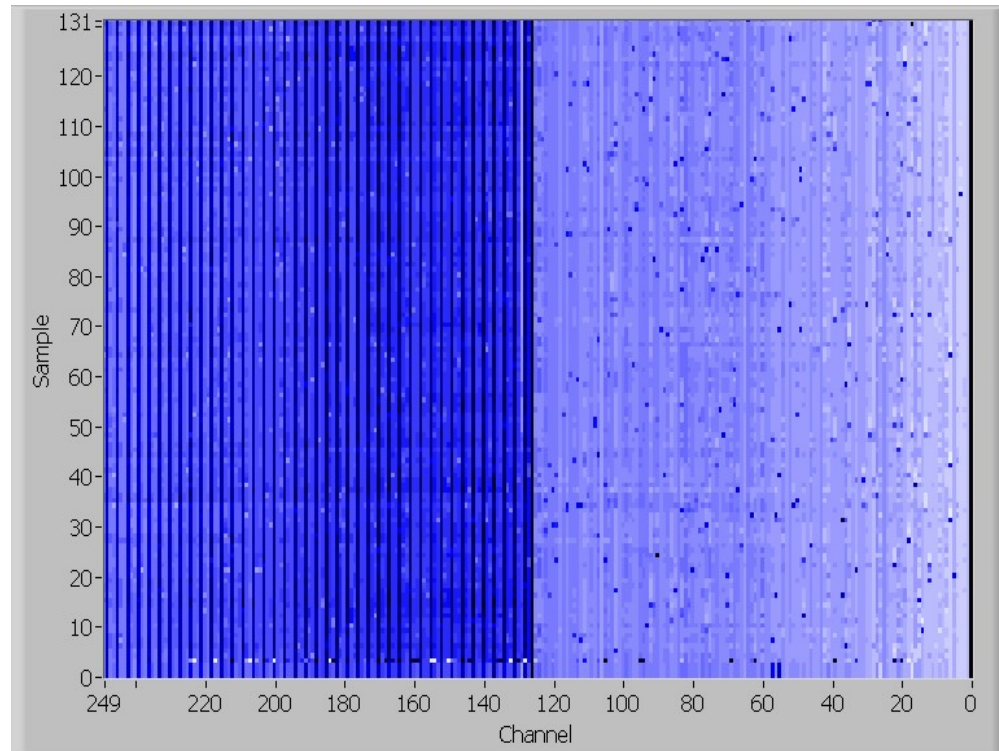
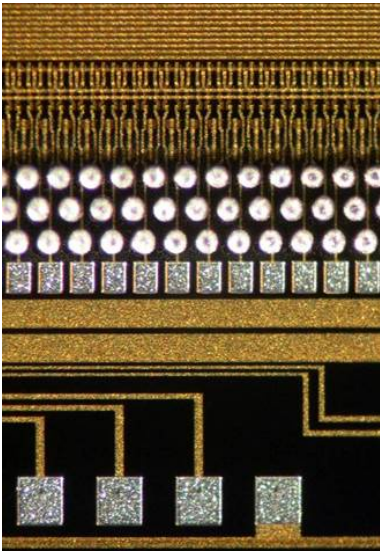
- Bump bonding performed by VTT:



- First time e2v CCDs bump bonded.

# CPC1 bump bonded to CPR1 readout chip

- Bump bonds are good, as visible under microscope...
- 6.9 keV X-ray hits, 1 MHz column parallel readout:

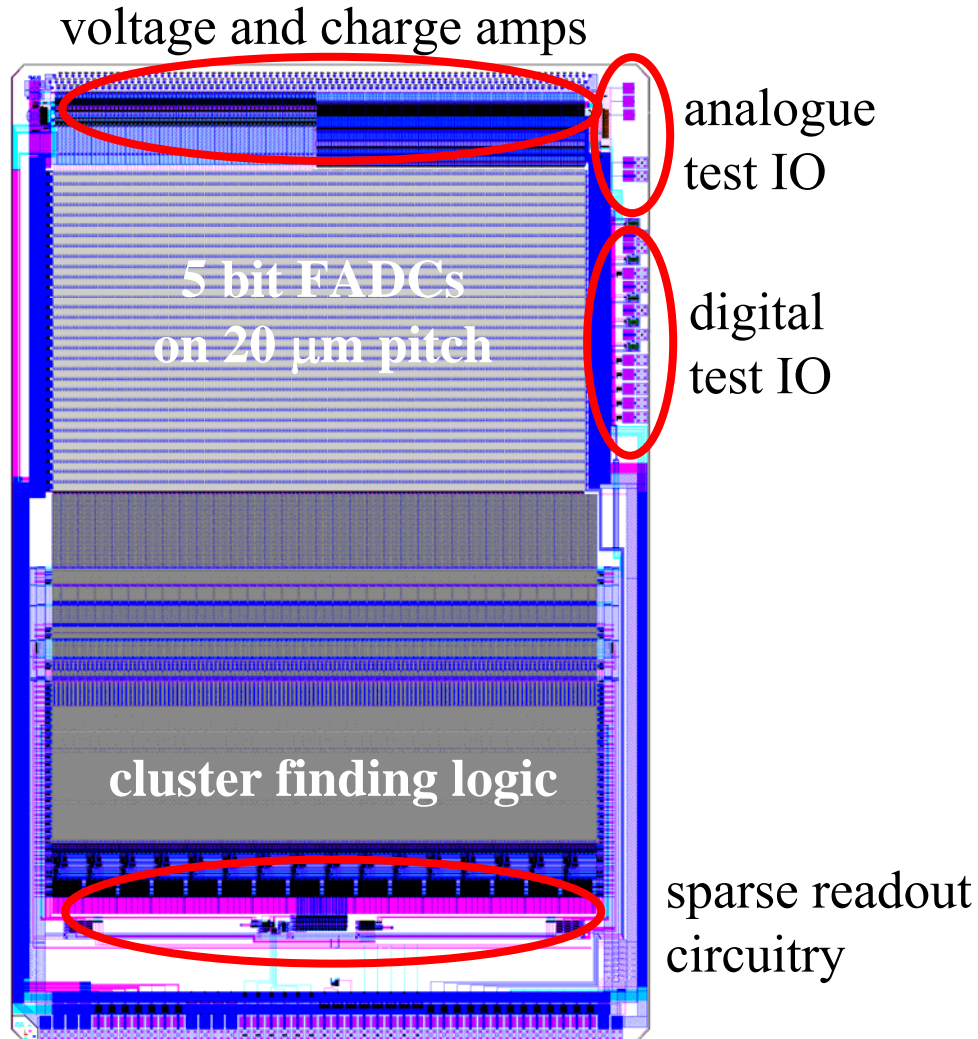


- ...but yield of functioning assemblies only 30%.

Inv. charge o/ps  
(+ ive signals)  
noise  $\approx 100 e^-$

Non-inv. volt. o/ps  
(- ive signals)  
noise  $\approx 60 e^-$

# Next generation CPCCD readout chip, CPR2

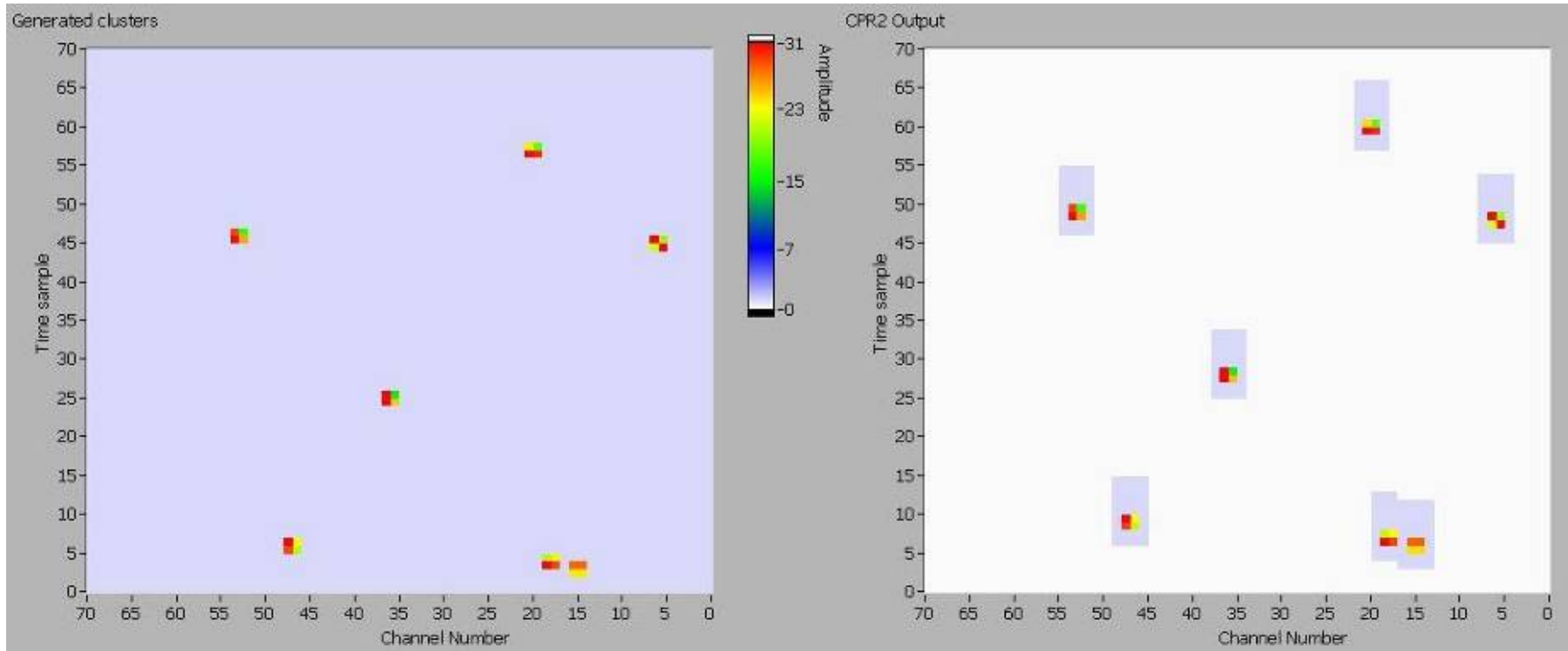


- CPR2 designed for CPC2 by the Microelectronics Group at RAL.
- All problems identified with CPR1 rectified.
- Many additional features to improve testing.
- Size:  $6 \times 9.5 \text{ mm}^2$ .
- IBM  $0.25 \mu\text{m}$  CMOS process.
- First tests now completed.

# Next generation readout chip – CPR2

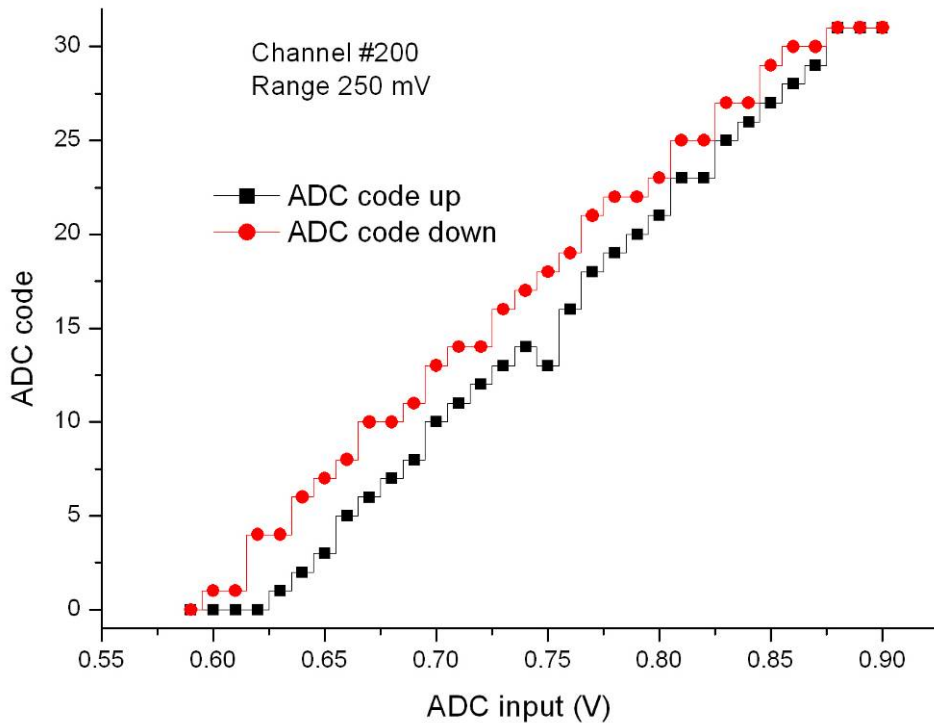
■ Test clusters in:

■ Sparsified data out:



# Next generation readout chip – CPR2

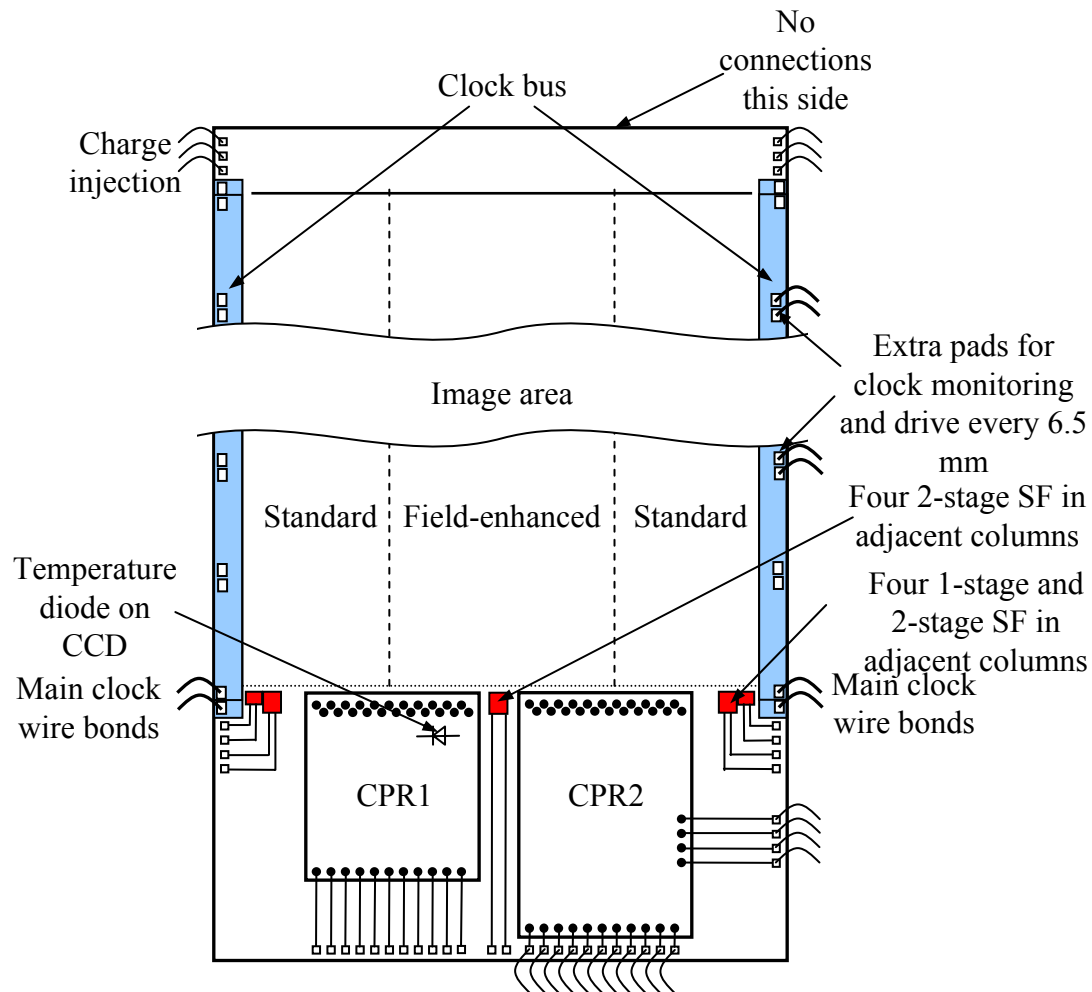
- Test analogue-to-digital conversion:



- Hysteresis in the ADC transfer curve:
  - ◆ Charge coupling between digital and analogue circuitry in the ADC comparators.
  - ◆ Should be much less than  $1 \times \text{LSB}$ .
- At least two ways to solve it for next chip, CPR2a:
  - ◆ Reduce transistor size (less gate charge).
  - ◆ Separate analogue and digital signals using switch.
- CPR2a design largely complete, start work on CPCCD drive: major challenge remaining for this sensor.



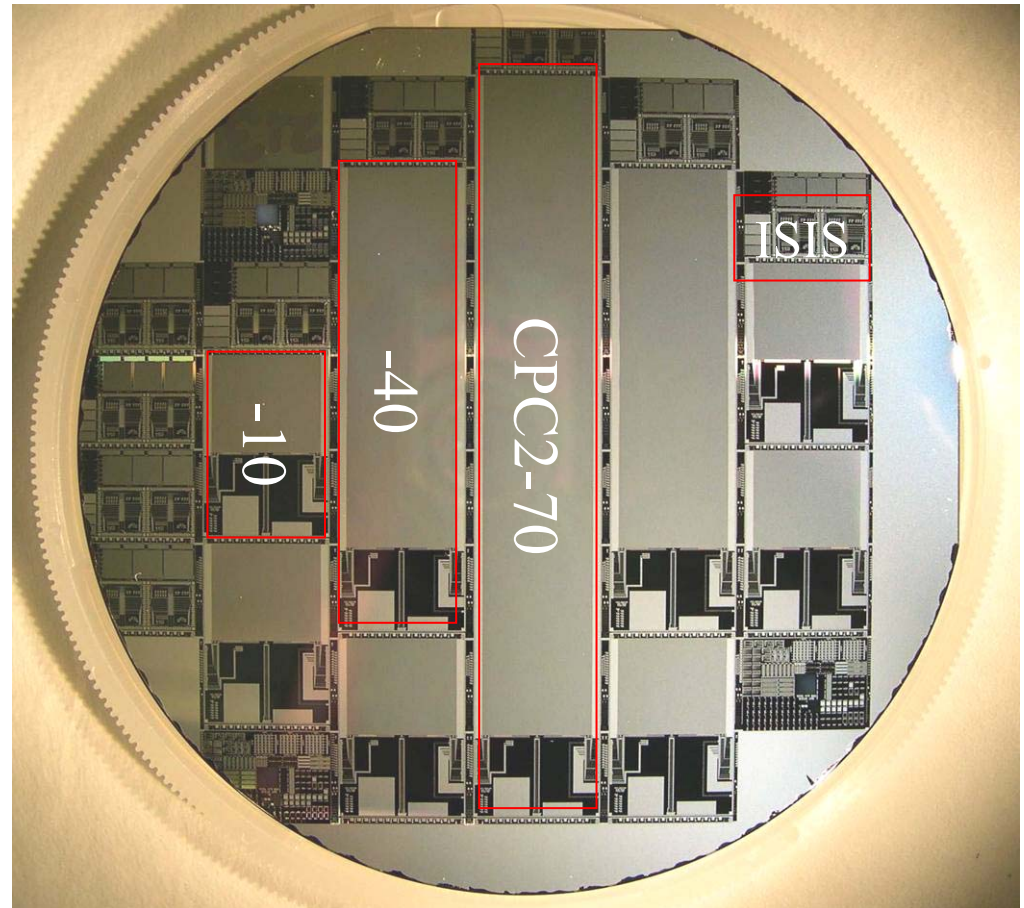
# Next generation CPCCD – CPC2



- Compatible with CPR1 and CPR2
- Two charge transport sections.
- Choice of epitaxial layers giving different depletion depths:  $100 \Omega \text{ cm}$  ( $25 \mu\text{m}$  thick) and  $1.5 \text{ k}\Omega \text{ cm}$  ( $50 \mu\text{m}$  thick)
- Design allows few MHz operation for CPC2-70.
- Hope to achieve 50 MHz with small CPC2s.

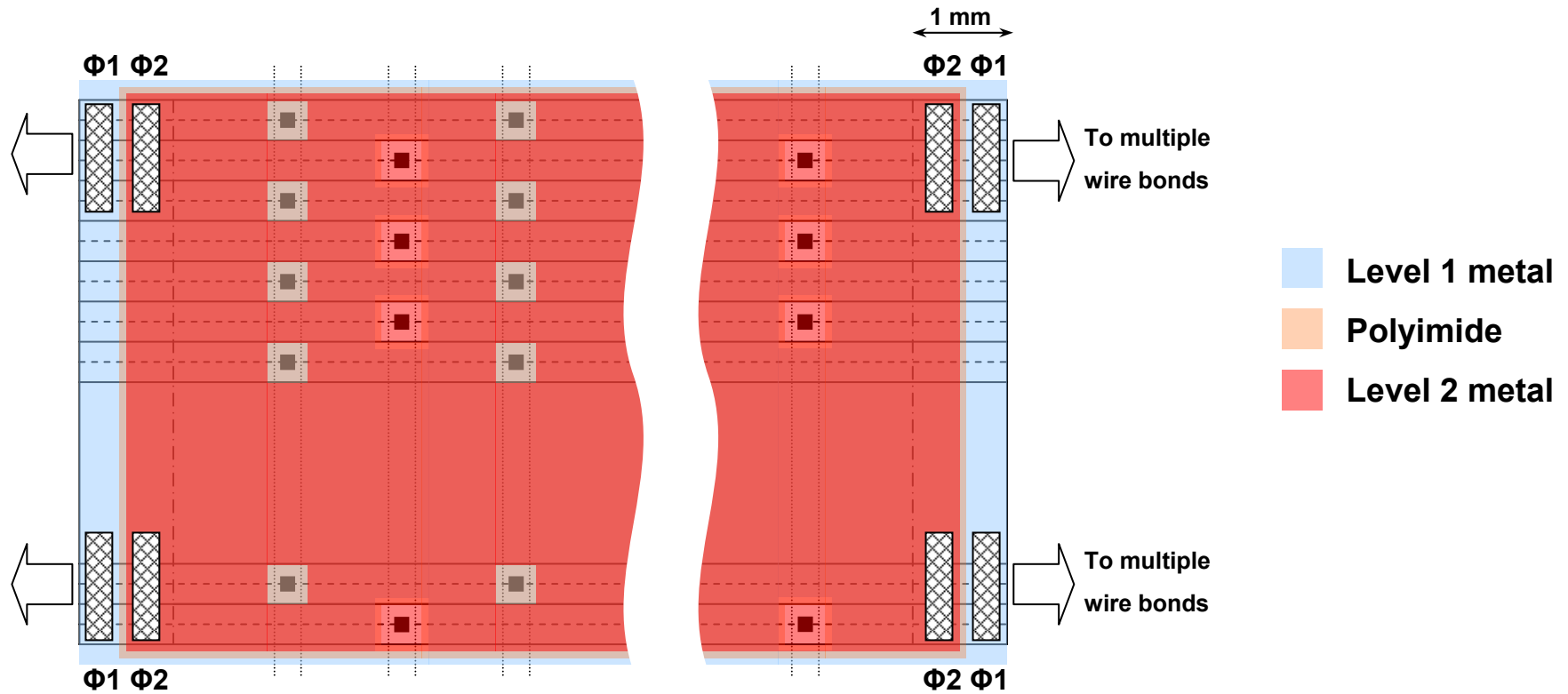
# CPC2

- Three chip sizes on CPC2 wafer:
  - ◆ CPC2-70:  $92 \times 15 \text{ mm}^2$  image area.
  - ◆ CPC2-40:  $53 \times 15 \text{ mm}^2$ .
  - ◆ CPC2-10:  $13 \times 15 \text{ mm}^2$ .



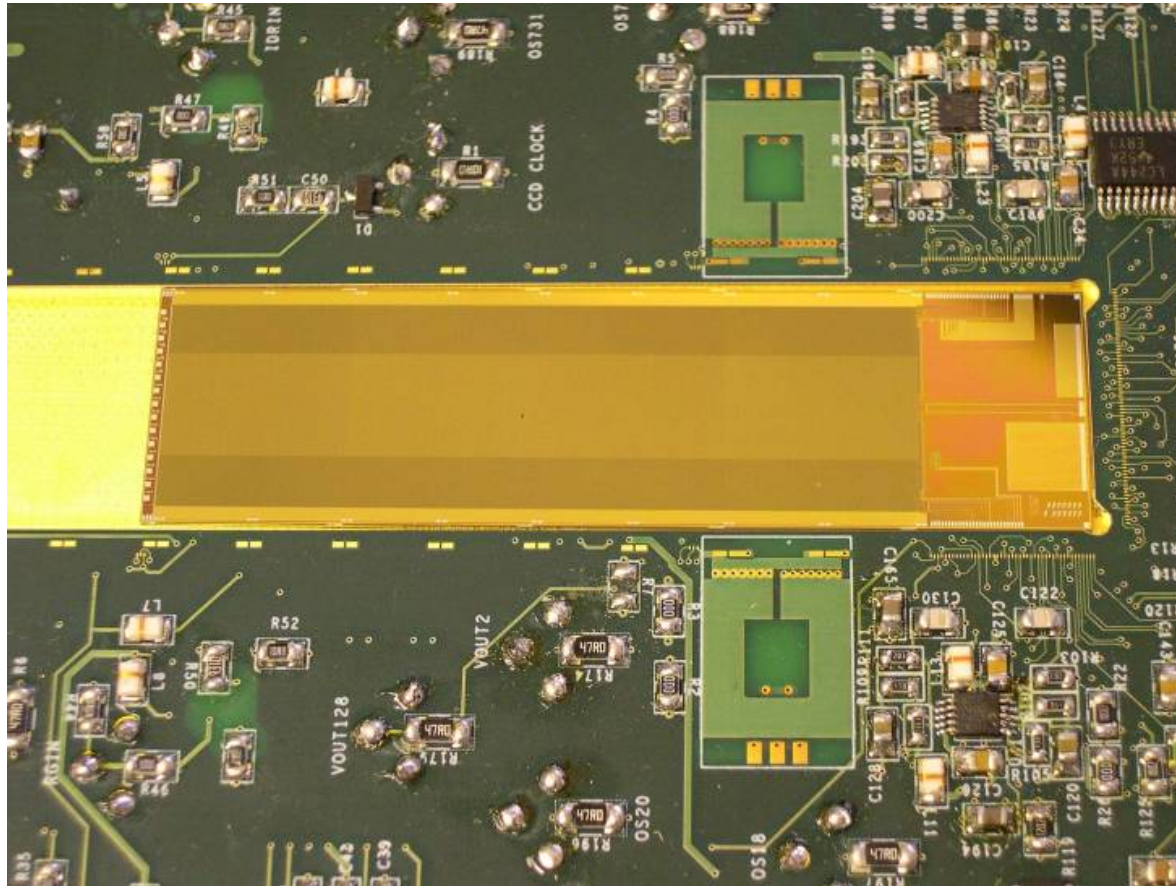
# CPC2 clock distribution

- Novel idea for high-speed clock propagation, “busline-free” CCD:



# CPC2

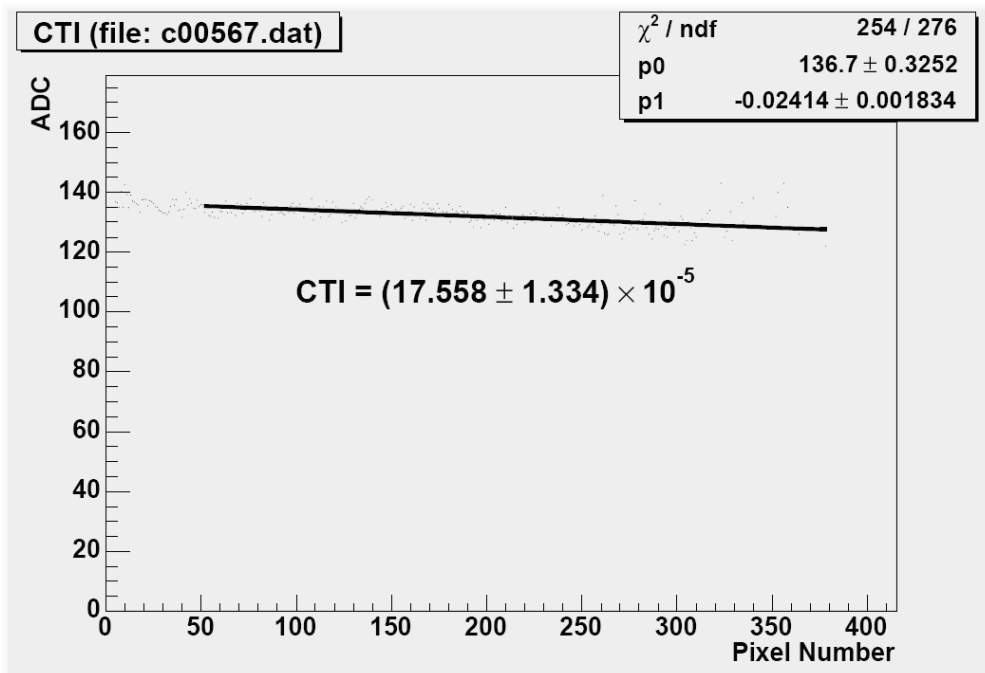
- CPC2-40 on motherboard awaiting testing:



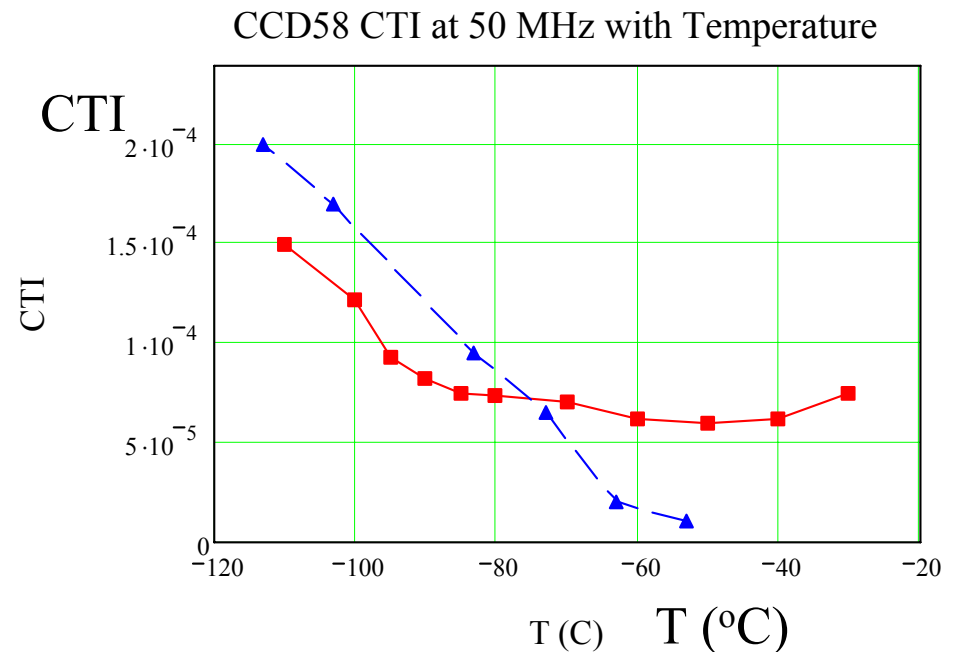
- (See Konstantin Stefanov's talk at Vertex05 for more details)

# CCD radiation hardness tests

- Study CTI in CCD58 before and after irradiation ( $^{90}\text{Sr}$  30 krad).
- Measure decrease in charge from  $^{55}\text{Fe}$  X-rays as func. of number of pixels through which charge transferred.



- Compare data with simulations performed using ISE-TCAD.

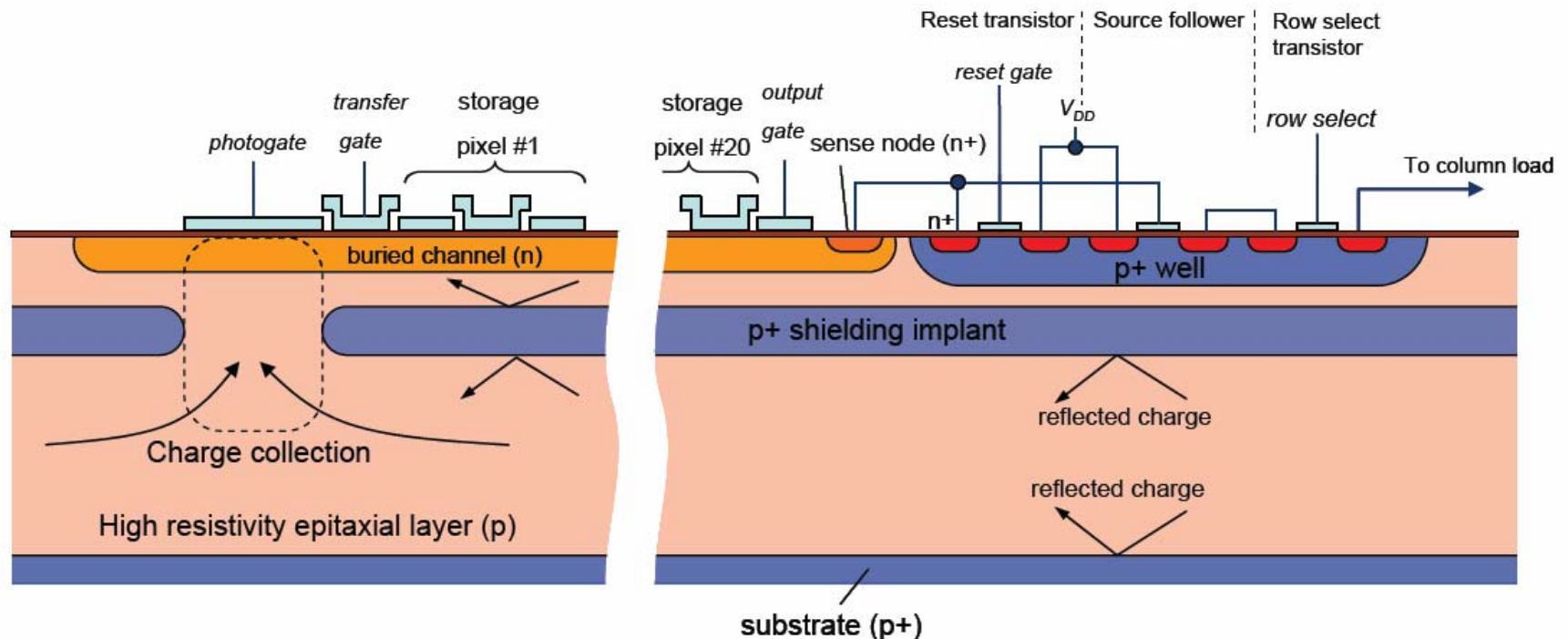


- Extend to CPCCD in 2006.



# Principle of the ISIS

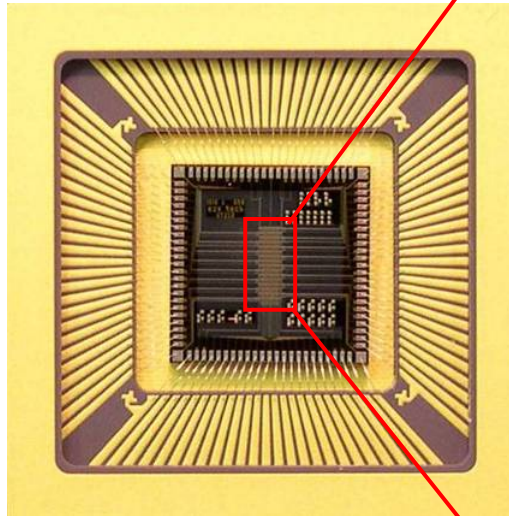
- CPCCD, charge-to-voltage conversion during bunch train, susceptible to pick-up?
- In-situ Storage Image Sensor (ISIS) eliminates this problem.
- Charge is collected under photogate, transferred to storage CCD 20 times during the 1 ms bunch train, then converted to voltage and read out in 200 ms quiet period after bunch train: column parallel readout at 1 MHz sufficient.



# First ISIS tests

- “Proof of principle” device designed by e2V technologies.
- Array of  $16 \times 16$  pixels with CCD storage register (5 cells) in each pixel.

- ISIS1 in 100-pin PGA carrier →

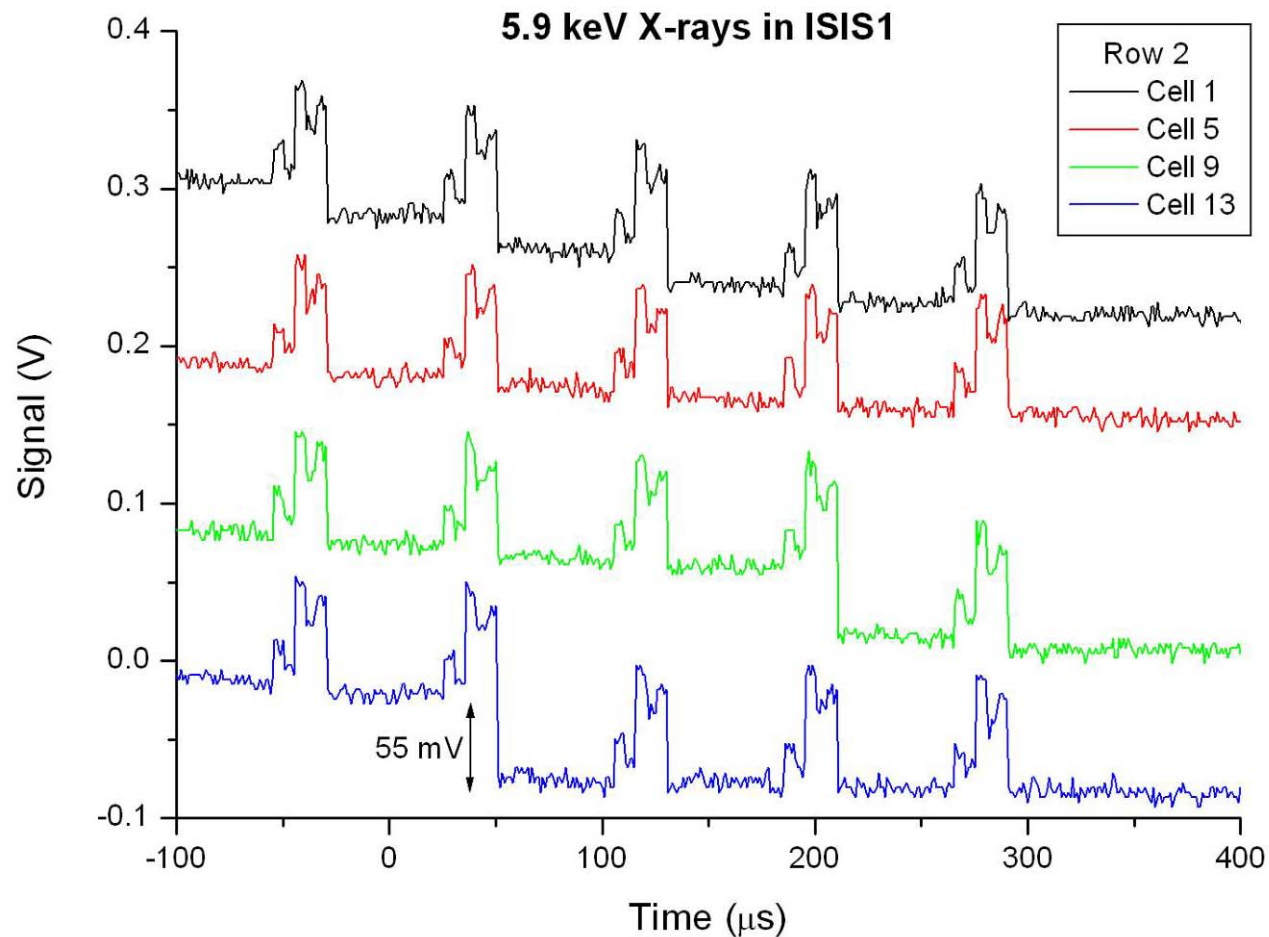


- Pixel pitch  $40 \times 160 \mu\text{m}^2$ , no edge logic (pure CCD process).
- Size  $\approx 6.5 \times 6.5 \text{ mm}^2$ .



# First X-ray signals from ISIS1

- Observe “steps” with correct amplitude:  $3 \mu\text{V}/e^- \times 1620 e^- \times \text{gain} (10) = 49 \text{ mV}$ .



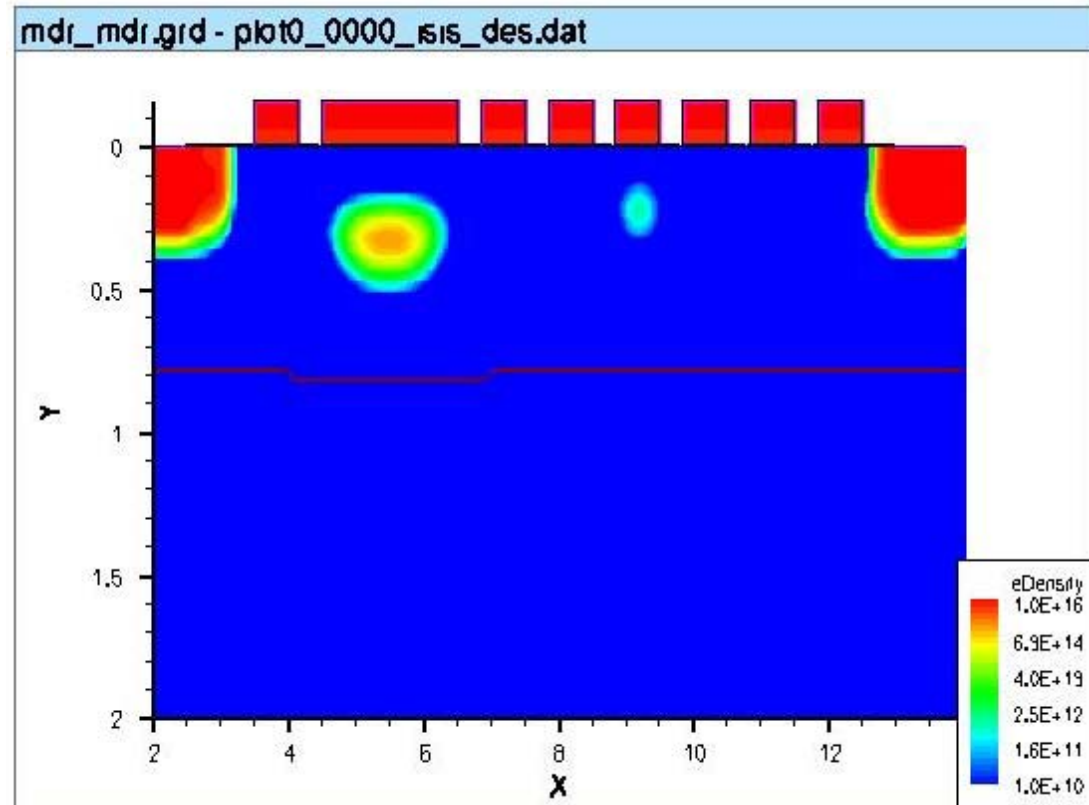
# Future ISIS developments

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- Next generation of ISIS will be CMOS based.
- Targeting 0.25  $\mu\text{m}$  (or 0.18  $\mu\text{m}$ ) process.
- Possible to use 6.5 nm  $\text{SiO}_2$  for both CCD and transistor gate dielectric?
- Maximum voltage 3.3 V.
- Non-overlapping poly-Si gates (0.35  $\mu\text{m}$  gap using 0.25  $\mu\text{m}$  design rules ).
- ISE-TCAD used to investigate achievable charge transfer efficiency, including simulation of implantation procedure.

# ISIS and the CMOS process

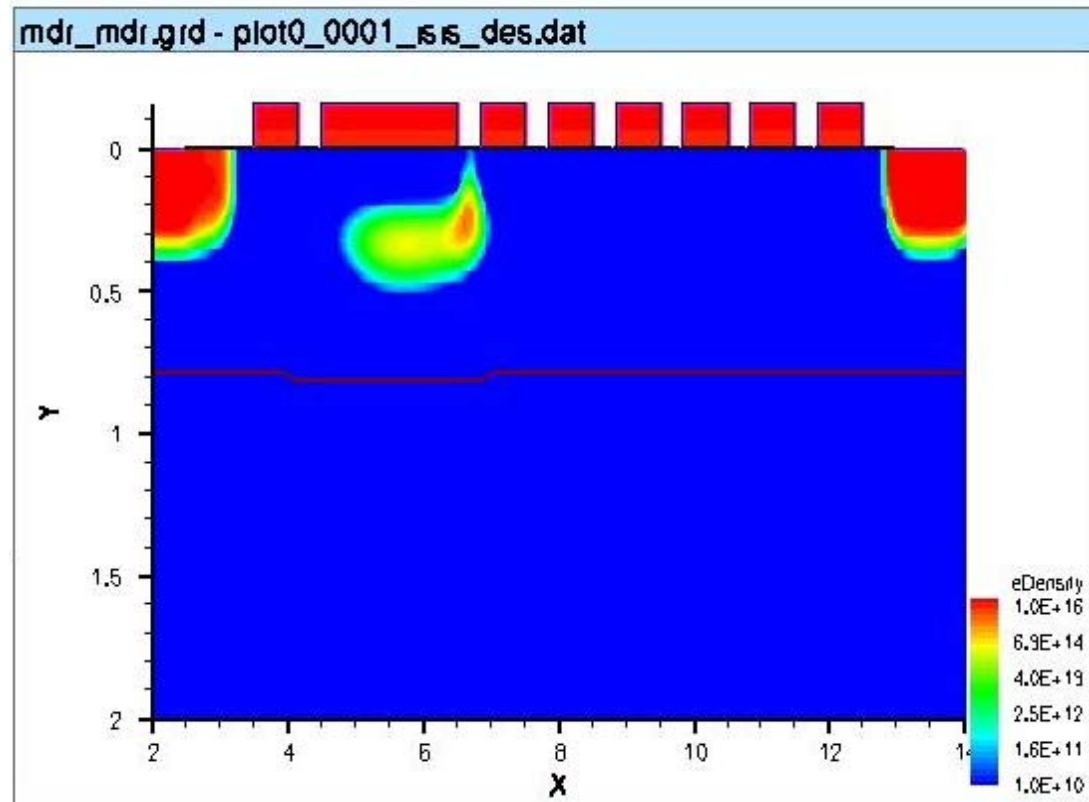
- Good charge transfer efficiency achieved in simulations.
  - ◆ Charge under photogate:





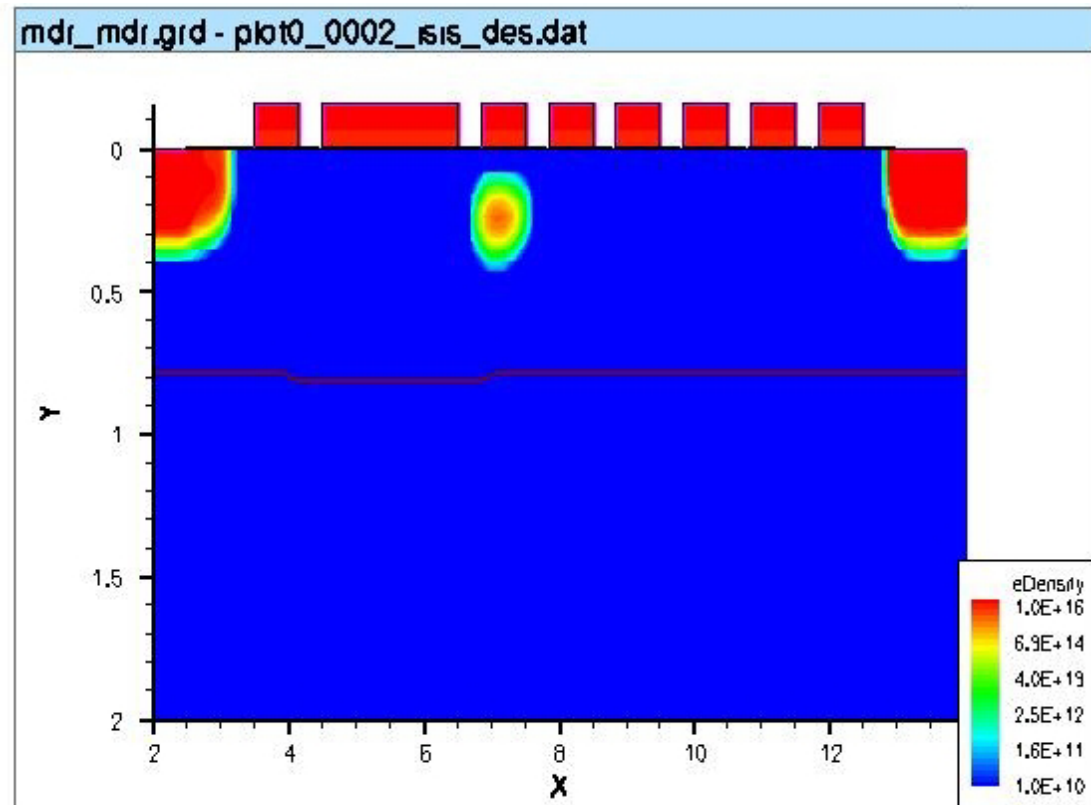
# ISIS and the CMOS process

- Good charge transfer efficiency achieved in simulations.
  - ◆ Charge transferring to first storage gate:



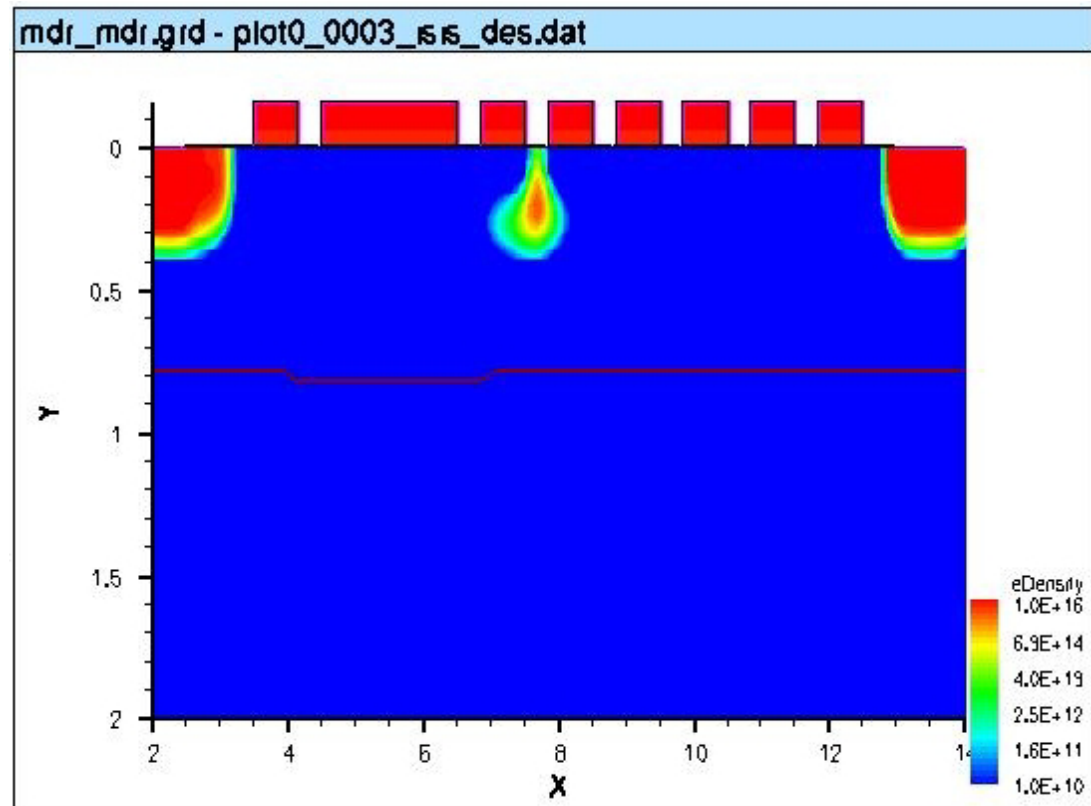
# ISIS and the CMOS process

- Good charge transfer efficiency achieved in simulations.
  - ◆ Charge under first storage gate:



# ISIS and the CMOS process

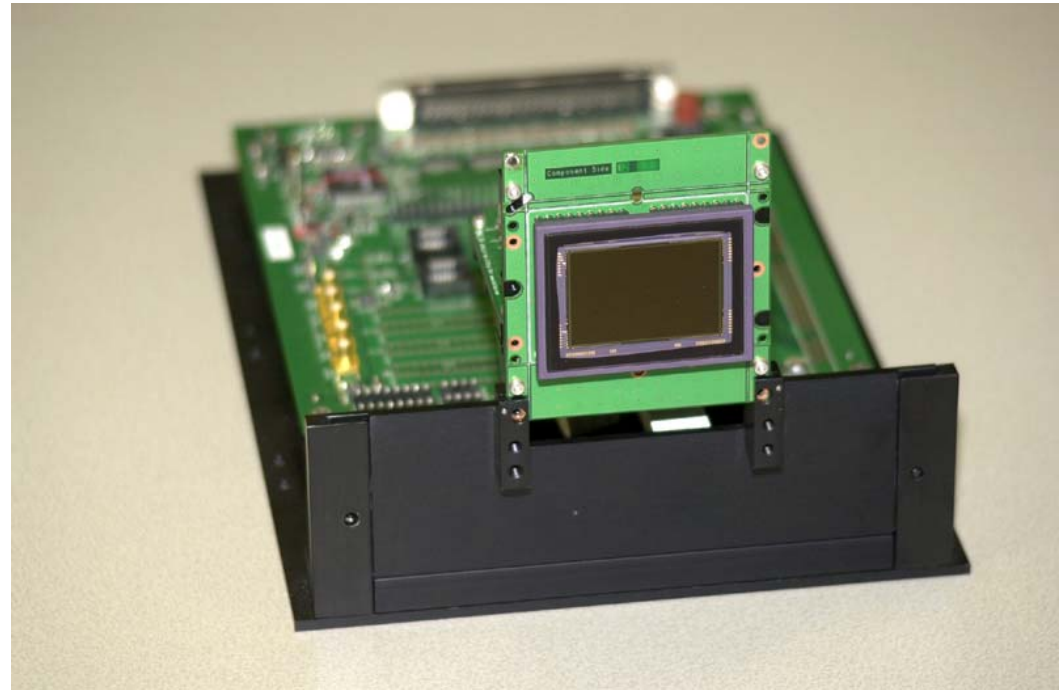
- Good charge transfer efficiency achieved in simulations.
  - ◆ Charge transferring to second storage gate:



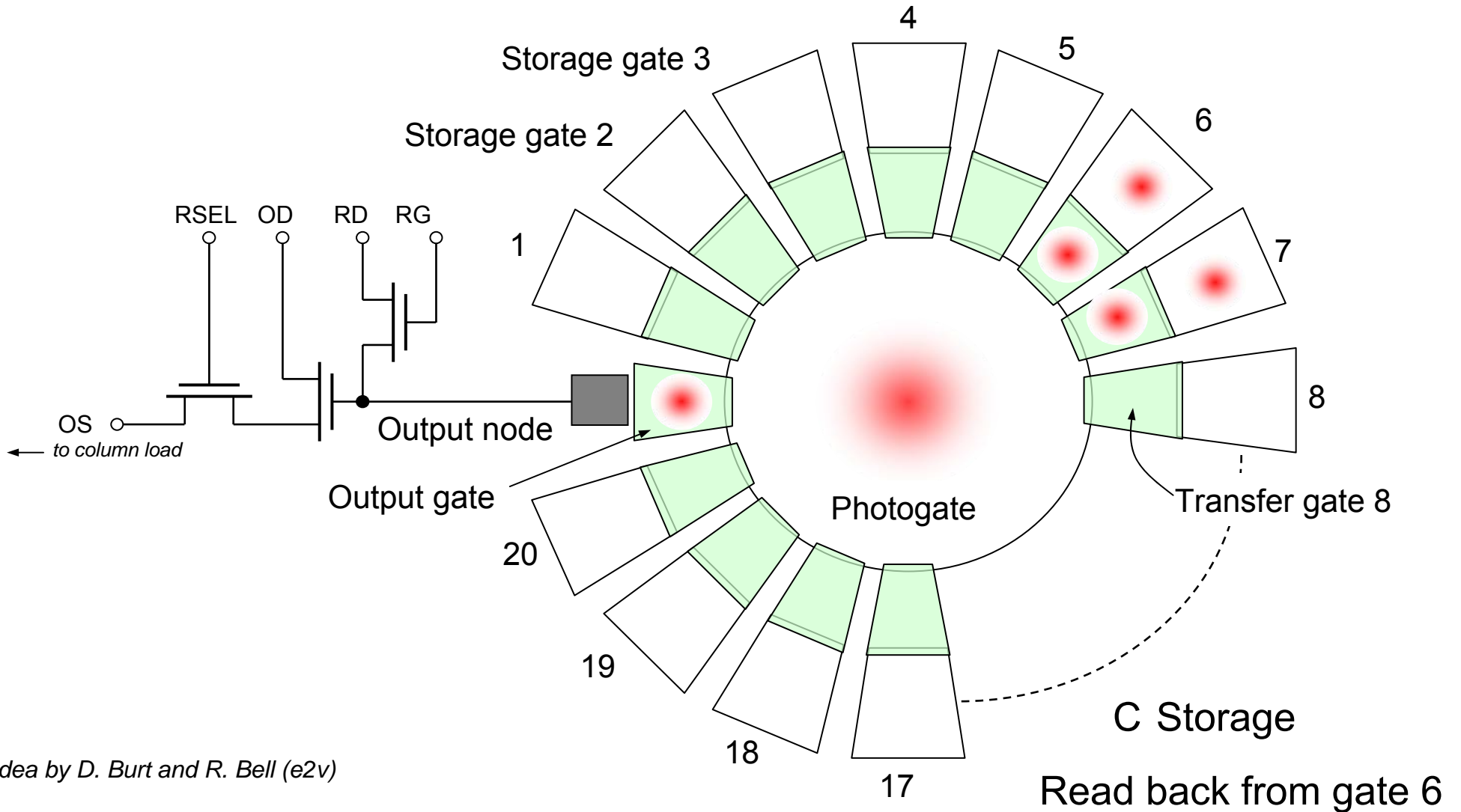
# Radiation hardness of device with non-overlapping gates

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- DALSA manufacture CCDs with non-overlapping gates.
- Have provided five CCDs which will allow studies of effects of electromagnetic radiation on these devices.
- Tests now starting at Rutherford.



# Alternative concept, the revolver

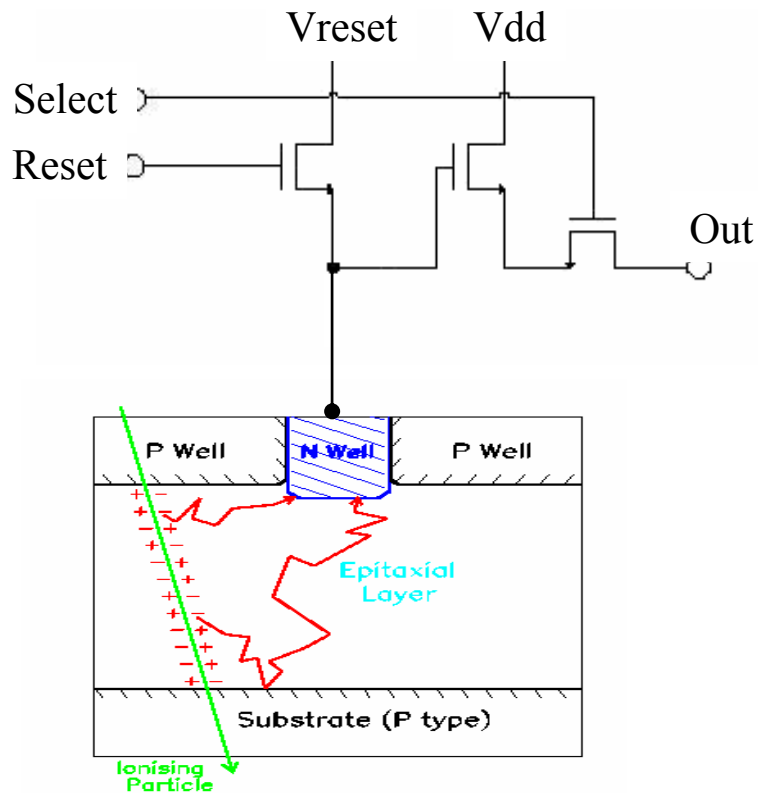


Idea by D. Burt and R. Bell (e2v)

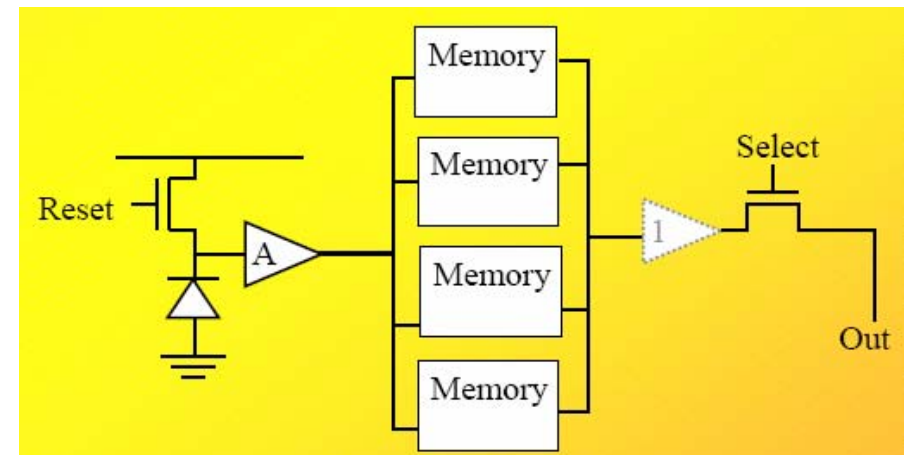
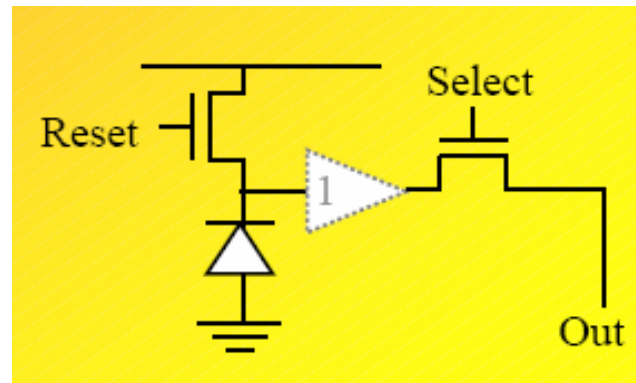


# Sensors – FAPS

- Monolithic Active Pixel Sensors also under investigation for ILC.

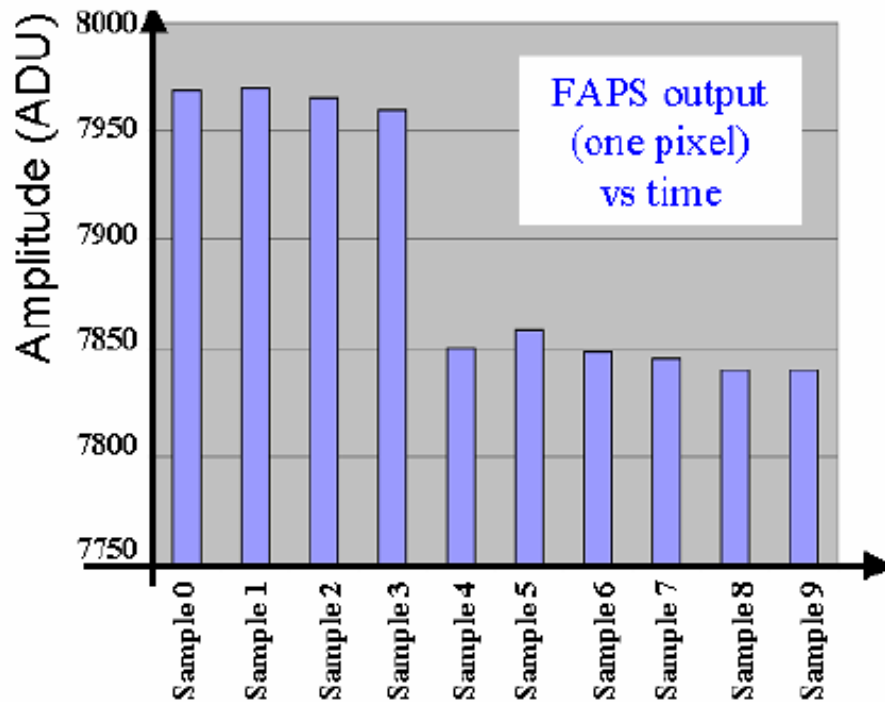


- Storage capacitors added to pixels: Flexible Active Pixel Sensors.

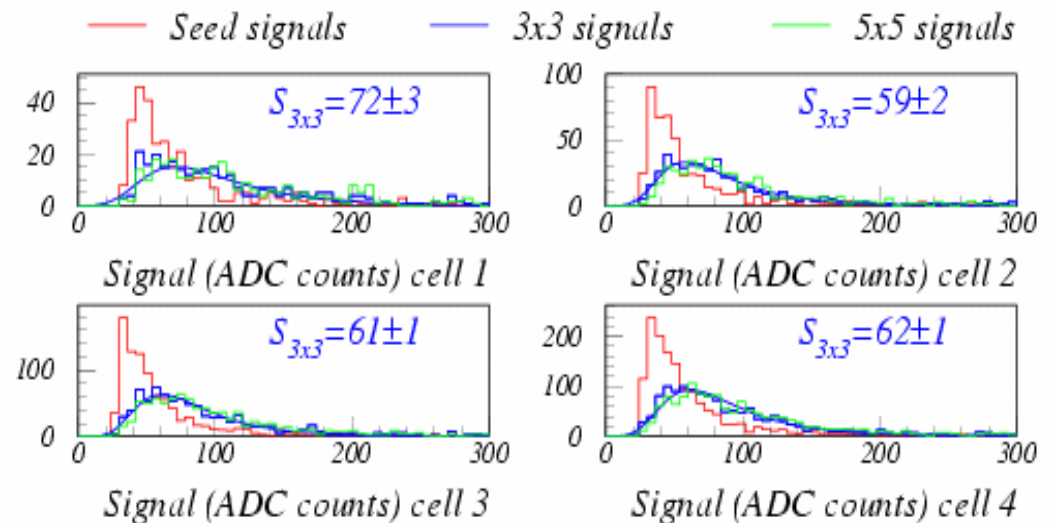


# Sensors – FAPS

- Present design “proof of principle”.
- Pixels  $20 \times 20 \mu\text{m}^2$ , 3 metal layers, 10 storage cells.
- Test of FAPS structure with LED:



- $^{106}\text{Ru}$   $\beta$  source tests:



- Signal to noise ratio  $\sim 14$ .
- Ongoing development of APS for scientific applications by MI3 collaboration.

# Mechanical studies

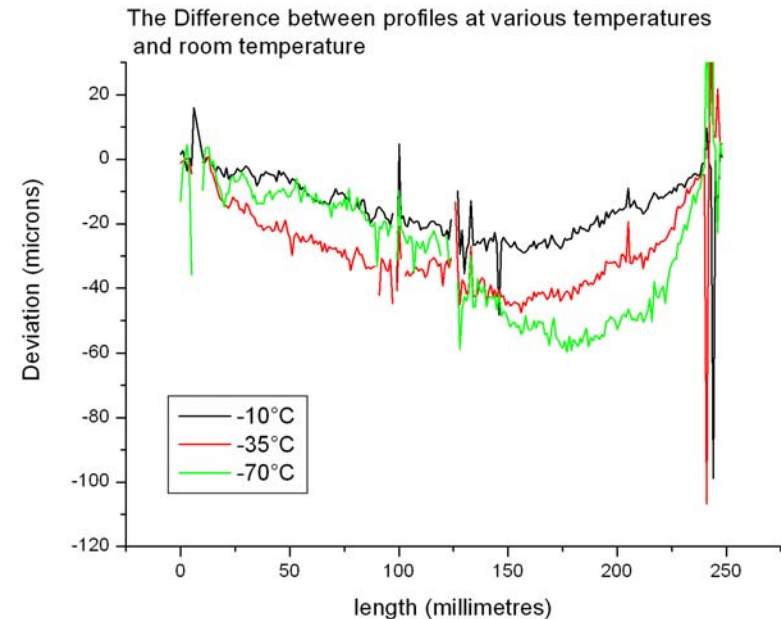
- “Stretched” sensor studies revealed thickness of  $\sim 50 \mu\text{m}$  Si needed.
- Beryllium results poor: bad match of thermal expansion with Si.
- Look at silicon “floating” on silicon carbide...



- ...and silicon/carbon-foam (reticulated vitreous carbon) sandwich.



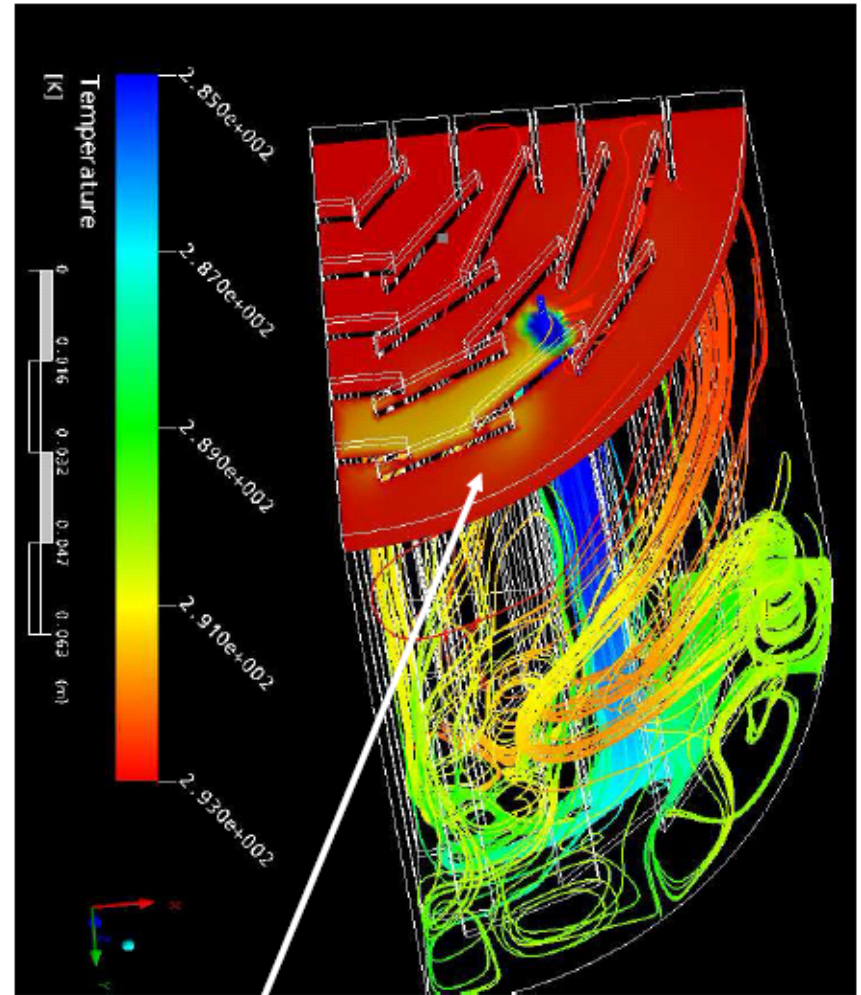
- Use “Nusil” silicone pillars to attach the silicon to the substrate.



Ladder	Material	X/Xo
Silicon on SiC foam ( $\sim 8\%$ density)	Silicon ( $25 \mu\text{m}$ ), SiC foam (1.5mm); silicone adhesive ( $\sim 300 \mu\text{m}$ in tiny pads)	0.16% ( $\sim 0.26\%$ at glue pad locations)
Silicon-RVC foam sandwich ( $\sim 3\%$ density)	Silicon ( $25 \mu\text{m}$ ) $\times 2$ ; RVC foam (1.5mm); silicone adhesive ( $\sim 100 \mu\text{m}$ in tiny pads) $\times 2$	0.08% ( $\sim 0.14\%$ at glue pad locations)

# Thermal studies

- CPCCD drive will exploit LC duty cycle of 0.5% to achieve low average power consumption: cool using  $N_2$  gas.
- Investigations of efficacy of cooling starting using quarter vertex detector thermal test rig.
- Simulations also under development to aid design of cooling system.

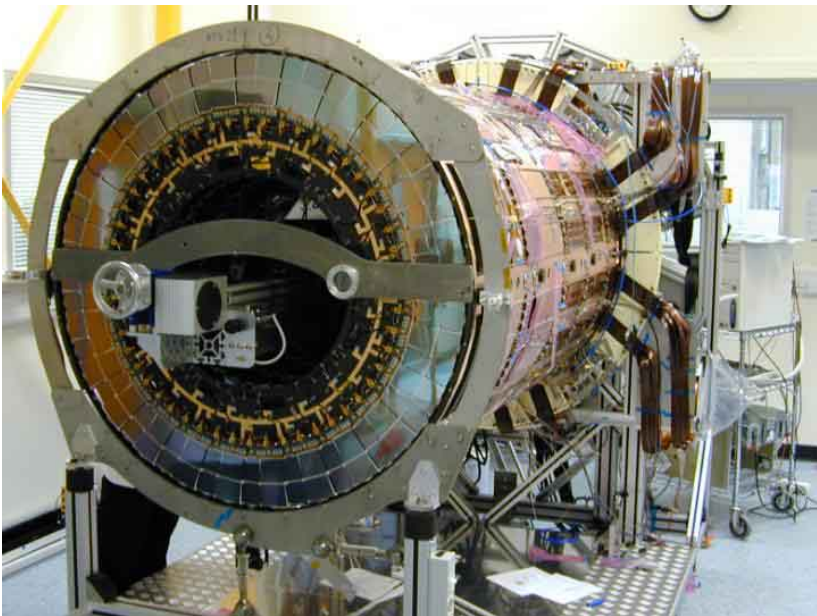


Temp profile across a section close to the inlet nozzle

# Other plans

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- Construction of ATLAS semiconductor track detector now nearing completion (e.g. endcap will be transported from Liverpool to CERN this month.)



- UK-ATLAS institutes have submitted a “Statement-of-Interest” for contributing to design and construction of new tracker for SLHC
- Proposal in 2009, build from 2010?
- Pixels: 4.0 m<sup>2</sup>, ~210 Mchannels
- Short strips (3 cm): 46 m<sup>2</sup>, ~30 Mchannels
- Long strips (12cm): 108 m<sup>2</sup>, ~11 Mchannels.
- Interest expressed by e2v.
- Small amount of funding available to develop MAPS based on SoI with Andor (Belfast).

# Summary

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- Studies of sensors for ILC in UK so far geared towards vertex detector (LCFI Collaboration).
- Studies of sensors, optimisation of vertex detector design for physics continuing.
- CCDs with column parallel readout look to be one sensor type which can provide the necessary performance.
- In-situ Image Storage Sensor offers high degree of immunity to possible RF pick-up problems, improved radiation hardness and relaxed readout speed requirements – first proof of principle device now tested.
- Active Pixel Sensor studies continuing mainly within MI3 framework for general science applications.
- Silicon/foam sandwich structures promise to provide very low mass support structures for silicon sensors.
- Studies of vertex detector cooling have now started.
- Increased interest in, and effort available for,  $\mu$ -strip tracker studies as ATLAS build draws to a close.